

Search Notes 	Application/Control No.	Applicant(s)/Patent under Reexamination
	10/074,193	SHI ET AL.
	Examiner	Art Unit
	Kevin Y. Kim	2634

INTERFERENCE SEARCHED			
Class	Subclass	Date	Examiner
375	229	6/9/05	Jew
333	28R		
375	296	6/10/05	Jew